

Franco Mori

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Profile

Born in Valparaiso (Chile) on 01/04/1951. Married with a 47-year-old daughter.

4 Years in USA, several months periods in United Kingdom and France.

25 Technical Publications in Physics and Electronics, 5 patents and record of inventions. Experience in the organization and managing of products and technology development at international level, transfer of technology, and related documentation (IP, qualifications, specifications etc.).

Working experience

Retired since 2012

2004- 2012 Fransys sas

Founder of the company with Anna Gazzari, provides Technical Translation Services to companies and agencies in the world.

2003- i-Sens Ltd (UK)

Senior Partner and Technical director charged with providing project management and other professional services in relation to Research and Development in the Industrial sector.

1999-2003 AMIC srl – (Italy)

Executive director

The company (recently acquired by MICROTEL SpA) operates in the field of systems for environmental and industrial process monitoring, providing customers with product development services and innovative solutions/components.

1992-1999 Magneti Marelli SpA - Divisione Elettronica (Italy and France)

Process Technology Manager, Innovation Vice-Director

Direct responsibility for about 40 researchers and scientist in the company research centres in Turin and Pavia (Italy), Nanterre and Chatellerault (France) and Belo Horizonte (Brasil). Responsibility for prototyping services and management of the process engineers in the manufacturing lines as well as sourcing engineers.

Responsible for:

- Defining and implementing the technology road map.
- Implementation of the innovation projects
- Specifying materials, process and tools.
- Leading projects for the installation and set up of new production lines in accordance with the yield, quality and financial targets of the company.
- Definition of design rules and process specifications

1989-1992 Marconi SpA (Group GEC) (Italy and UK)

Process Technology Centre Manager

Responsibility for approximately 20 technicians and researchers in Italy.

Responsibility for engineering and prototyping of new products in civil and military telecommunications, new processes development and their introduction into production lines. Fields of activity: Multi-layer Printed Board manufacturing, Surface Mount assembling, Micro Electronics Modules, Hybrid Circuits technologies, Fibre Optics Systems, Microwaves Modules.

Responsible for:

- The coordination of technology development projects in cooperation with GEC centres in Wembley and Chemsford (UK) and with the Welding Institute of Cambridge.
- Implementation of the innovation projects
- Specifying materials, process and tools.
- Leading projects for the installation and set up of new production lines in accordance with the yield, quality and financial targets of the company.
- Definition of design rules and process specifications

1982-1989 3M SpA Italy– 1986-1988 relocated at 3M Corp.St.Paul MN (USA)

Senior specialist with a mainly technical role in the Imaging Division, responsible for:

- Managing projects and people in an international environment.
- Responsible for the development of new electronic image pickup devices and products for acquiring and processing digital radiographic images.

1976-1981 ST Microelectronics (Italy)

Researcher in the field of materials and processes for semiconductor devices manufacturing.

Responsible for a small team active in the field of ion implantation.

Education

1975 University of Genoa – Degree in Physics 110/110

1969 Liceo C. Colombo - Maturità Classica 54/60

Additional information

Languages

Italian: mother tongue

French: fluent

English: fluent

Spanish: basic knowledge

Courses:

Centro formazione FIAT di Marentino:

Leadership, Lean Production, SPC, TQM.

Target Cost/Target Profit, Value Engineering

Open University: Fundamentals of senior management

Publications

- “A search for low temperature standard resistance alloys” Proc. Int. Cryog. Eng. Conf. 1976 6 190-3.
- “Si and SiO₂ plasma etching” 6 Congresso AIV Bari 1979
- “Plasma techniques in the field of semiconductors” Elettron. Oggi 1982 10 pp 59-65.
- “Metal/Si Interactions” ESDERC 79- York 1979
- “Molybdenum silicide: is it suitable for interconnection in VLSI?” Proc. Electrochem. Soc. 1981 81-5 608 22.
- “Refractory silicide interconnections” 7 Congresso AIV Bressanone 1981.
- “Impurity effects in molybdenum silicide formation” Thin Solid films 1982 94(1) 59-65.
- “Undercut in a CF₄-based high pressure polysilicon plasma etch” Jpn.J.Appl.Phys. 1983 part1 22 712-18
- “Fast silicon p-doped low temperature bolometer” Cryogenics 1984 24 681-3
- “Large area Image Pick-up Devices” Proc. Graphic Tech S. Worldwide Scientific Conference University Arms Hotel Cambridge July 13-17 1987
- “Multichip modules – Binomio Velocità-Potenza” Productronica Nov. 1991.
- 3M Record of Invention EIL 188 High Quantum Efficiency Amorphous Silicon Flexible Schottky-barrier photodiode” 12 June 1988
- 3M Record of Invention GRL 304 “Electronic Thermal Image Sensor” 6 october 1987
- 3M Record of Invention IIL 30 “Method of fabricating Pt-Si/Amorphous photodiodes” 30 March 1988.
- 3M Record of Invention III 18 “ Amorphous Germanium-based Schottky-barrier Infrared Detectors” 15 March 1988.
- 3M Record of Invention EIL 193 “ Amorphous Silicon Infrared Detectors” 9 July 1987. 3M Record of Invention FL 379 “Large Area Solid State Detector Suitable for X-Ray Diagnostic and Industrial Imaging and Process for Obtaining such Detector” 19 October 1988

- 3M INFORMATION&IMAGING TECHNOLOGIES SECTOR GRAPHIC RESEARCH LABORATORY Patent Proposal IILX "Amorphous Silicon Schottky Barrier Xray sensor" 8 August 1988
- Brevetto(*) per invenzione industriale -Ufficio Italiano Brevetti e Marchi al numero 01297714, avente ad oggetto: "Sonda Microelettronica per il controllo ed il monitoraggio automatico e contemporaneo di diversi parametri chimico-fisici di liquidi e loro trasmissione a centrali remote"
- European Patent Application at the European Patent Office EP 0 933 635 A3 Priority 17 December 1997 IT GE970106 "Microelectronics probe for automatic, simultaneous control and monitoring of several chemical physical parameters of liquid substances, and their transmission to a remote terminal"
- United States Patent 5291036 "Amorphous silicon sensor"